Japan TC Chapter of
Assembly & Packaging Global Technical Committee
Meeting Summary and Minutes

Japan Standards Winter 2016 Meetings
Friday, February 5, 2016, 1:30 p.m. – 3:00 p.m. [JST]
SEMI Japan office, Tokyo, Japan

Next Committee Meeting
Friday, June 10, 2016, 3:00 p.m. – 5:00 p.m. [JST]
Japan Standards Summer 2016 Meetings, Tokyo, Japan

Committee Announcements (optional)
None

Table 1 Meeting Attendees
* Italic indicates virtual participants
Co-Chairs: Kazunori Kato (AiT), Masahiro Tsuriya (iNEMI)
SEMI Staff: Chie Yanagisawa (SEMI Japan)
Attendee: 9 + SEMI: 1

<table>
<thead>
<tr>
<th>Company</th>
<th>Last</th>
<th>First</th>
<th>Company</th>
<th>Last</th>
<th>First</th>
</tr>
</thead>
<tbody>
<tr>
<td>Acteon</td>
<td>Komatsu</td>
<td>Shoji</td>
<td>iNEMI</td>
<td>Tsuriya</td>
<td>Masahiro</td>
</tr>
<tr>
<td>AIST</td>
<td>Kada</td>
<td>Morihiro</td>
<td>Micron Memory Japan</td>
<td>Sonobe</td>
<td>Kaoru</td>
</tr>
<tr>
<td>AIST</td>
<td>Shimamoto</td>
<td>Haruo</td>
<td>Tokyo Electron</td>
<td>Shibuta</td>
<td>Taki</td>
</tr>
<tr>
<td>AiT</td>
<td>Kato</td>
<td>Kazunori</td>
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<tr>
<td>Asahi Glass</td>
<td>Takahashi</td>
<td>Mamoru</td>
<td></td>
<td></td>
<td></td>
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<tr>
<td>DISCO</td>
<td>Masuchi</td>
<td>Sumio</td>
<td>SEMI Japan</td>
<td>Yanagisawa</td>
<td>Chie</td>
</tr>
</tbody>
</table>

* alphabetical order by company name

Table 2 Leadership Changes

<table>
<thead>
<tr>
<th>Group</th>
<th>Previous Leader</th>
<th>New Leader</th>
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<tbody>
<tr>
<td>None</td>
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</table>

Table 3 Ballot Results (or move to Section 4, Ballot Review)
Passed ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review.
Failed ballots and line items were returned to the originating task forces for re-work and re-balloting.

<table>
<thead>
<tr>
<th>Document #</th>
<th>Document Title</th>
<th>Committee Action</th>
</tr>
</thead>
<tbody>
<tr>
<td>None</td>
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</tbody>
</table>

Table 4 Authorized Ballots (or move to Section 7, New Business)

<table>
<thead>
<tr>
<th>#</th>
<th>When</th>
<th>SC/TF/WG</th>
<th>Details</th>
</tr>
</thead>
<tbody>
<tr>
<td>None</td>
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</table>

Table 5 Authorized Activities (or move to Section 7, New Business)

<table>
<thead>
<tr>
<th>#</th>
<th>Type</th>
<th>SC/TF/WG</th>
<th>Details</th>
</tr>
</thead>
<tbody>
<tr>
<td>None</td>
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</tbody>
</table>
Table 6 New Action Items (or move to Section 8, Action Item Review)

<table>
<thead>
<tr>
<th>Item #</th>
<th>Assigned to</th>
<th>Details</th>
</tr>
</thead>
<tbody>
<tr>
<td>20160205-#01</td>
<td>Kazunori Kato (AiT)</td>
<td>To contact to Mikio Kiyono (AET) for the activity status of Electromagnetic Characterization Study Group.</td>
</tr>
<tr>
<td>20160205-#02</td>
<td>Masahiro Tsuriya (iNEMI)</td>
<td>To send the ballot drafts of revision to SEMI G20, SEMI G21 and SEMI G41 to Kazunori Kato in order that Kazunori Kato would check them with SEMI Staff if they are OK and then send to Shinko to ask for work for revision to those Standards.</td>
</tr>
<tr>
<td>20160205-#03</td>
<td>Masahiro Tsuriya (iNEMI)</td>
<td>To check if SEMI G31, SEMI G45, SEMI G49 are OK, and then ask for document review to Hitachi Chemicals.</td>
</tr>
</tbody>
</table>

Table 7 Previous Meeting Actions Items (or move to Section 8, Action Item Review)

<table>
<thead>
<tr>
<th>Item #</th>
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<th>Details</th>
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</thead>
<tbody>
<tr>
<td>None</td>
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1 Welcome, Reminders, and Introductions

Masahiro Tsuriya (iNEMI) called the meeting to order at 1:30 p.m. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

2 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting.

Motion: To approve the minutes of the previous meeting as written.

By / 2nd: Kazunori Kato (AiT) / Sonobe Kaoru (Micron Memory Japan)

Discussion: None

Vote: 7 in favor and 0 opposed. Motion passed.

3 Liaison Reports

3.1 3DS-IC TC Chapters

Half a year passed since the 3DS-IC Japan TC Chapter started its activity, the liaison reports of related TC Chapters would not be presented at this TC Chapter meeting.

3.2 SEMI Staff Report

Chie Yanagisawa (SEMI Japan) gave the SEMI Staff Report. Of note:

- Global SEMI Events
- Global Standards Meetings Schedule
- Ballot Critical Dates
- Publication Update
- A&R Ballot Review
- New Requirements/Process Reminders for TC Chapter Meetings
- Contact Information

Attachment: 01_SEMI Staff Report 20160203_r1
4 Ballot Review

None

5 Subcommittee & Task Force Reports

5.1 GCS
Kazunori Kato (AiT) reported that there was no update.

5.2 Electromagnetic Characterization Study Group
No report was made at this TC Chapter meeting.

Action Item 1: Kazunori Kato (AiT) to contact to Mikio Kiyono (AET) for the activity status of Electromagnetic Characterization Study Group.

5.3 Japan 450mm Assembly & Test Die Preparation Task Force
Sumio Masuchi (DISCO) reported that there was no update.

5.4 Thin Chip Handling Task Force
Haruo Shimamoto (AIST) reported that Ballot #5835 “New Standard: SPECIFICATION FOR ADHESIVE TRAY USED FOR THIN CHIP HANDLING” passed at A&R in December 2015 and was published as SEMI G97-0116 in January 2016. He also reported that Doc.5836 “New Standard: Test Method for Adhesive Strength for Adhesive Tray Used for Thin Chip Handling” would be prepared for ballot draft review at the next TF meeting to be held on February 25.

5.5 Packaging 5 Year Review Task Force
The details would be reported at the Old Business section of this meeting.

5.6 3D-IC Study Group
No report was made at this TC Chapter meeting.

5.7 Fiducial Mark Interoperability Task Force
Sumio Masuchi (DISCO) reported the task force completed the Revision to SEMI T7-0415.

Attachment: 02_20151216FMI-TF-Report_r1

6 Old Business

6.1 5 Year Review Check
Kazunori Kato (AiT) mentioned that there were many Assembly & Packaging documents to be reviewed, but due to the time constraints the TC Chapter should assigned to some members for review for the next step.

Action Item 2: Masahiro Tsuriya (iNEMI) to send the ballot drafts of revision to SEMI G20, SEMI G21 and SEMI G41 to Kazunori Kato in order that Kazunori Kato would check them with SEMI Staff if they are OK and then send to Shinko to ask for work for revision to those Standards.

Action Item 3: Masahiro Tsuriya (iNEMI) to check if SEMI G31, SEMI G45, SEMI G49 are OK, and then ask for document review to Hitachi Chemicals.

6.2 SNARF Project Period Check
There was no SNARF that three year passed since its initial approval.
7 New Business

7.1 Standardization for Power Devices

Masahiro Tsuriya (iNEMI) mentioned that the TC Chapter would discuss the possibility of standardization for power devices at the next TC Chapter meeting.

8 Action Item Review

8.1 Open Action Items

There was no open action item.

8.2 New Action Items

Chie Yanagisawa (SEMI Japan) reviewed the new action items. They are listed on the Table 6 above.

9 Next Meeting and Adjournment

The next meeting of the Assembly & Packaging Japan TC Chapter is scheduled for Friday, June 10, 2016, 3:00 p.m. – 5:00 p.m. at Japan Standards Summer Meetings at SEMI Japan office in Tokyo, Japan.
Respectfully submitted by:
Chie Yanagisawa
Senior Standard Coordinator
SEMI Japan
Phone: +81.3.3222.5863
Email: cyanagisawa@semi.org

Minutes approved by:
Kazunori Kato (AiT), Co-chair May 14, 2016
Masahiro Tsuriya (iNEMI), Co-chair May 16, 2016

Table 8 Index of Available Attachments

<table>
<thead>
<tr>
<th>#</th>
<th>Title</th>
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<tbody>
<tr>
<td>01</td>
<td>SEMI Staff Report 20160203_r1</td>
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</tr>
<tr>
<td>02</td>
<td>20151216FMI-TF-Report_r1</td>
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#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.